

SIRIUS[™] Diffusion Furnace Systems



SYSTEM

Three quartz process tubes for up to 8" dia./156mm square processing (270x280mm dia.)

Tube Level 1 – N Type Deposition (POC13)

Tube Level 2 – Dry Oxidation

Tube Level 3 – P-Type Deposition (BBr3) + Drive-In

System capablities and details

Liquid dopant sources-POCl₃,BBr₃.

System Temperature Capability: $400-1100^{\circ}$ CTemperature Repeatability: ± 1.0 , type "R" TC

18" (46cm) thermal flatzone, temperature stability full length of flatzone = $\pm 1.0^{\circ}$ C

Mass Flow Controlled gas systems

Liquid source temperature controllers on POCl3 and BBr3 tube levels

Digital process and temperature controllers per tube level

HOST computer included Stainless steel scavenger per tube level

_Digital Temperature/Process Sequence Controller .

Karthick Murukesan, Electrical Engineering, IIT-Bombay, NCPRE



IIT-B system



Reference diagram as given by Protemp